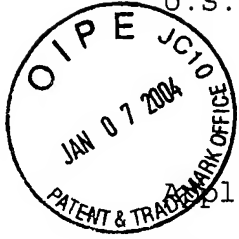


image

1765  
2874

U.S.S.N. 10/077,720



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yi-Nien Su et al.

Group Art Unit: 2814

Serial No.: 10/077,720

Examiner: A.K. Alanko

Filed: 02/15/2002

In Response to Office Action  
Dated: 10/07/2003

For: A METHOD FOR IMPROVED PLASMA ETCHING CONTROL

Attorney Docket No.: 67,200-478

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450

Date: Jan. 5, 2004

RESPONSE TO OFFICE ACTION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 10/07/2003,  
please enter the following amendments and consider the following  
remarks. The Commissioner is hereby authorized to charge Deposit  
Account No. 50-0484 any fee due as a result of this response.